

# AFM beyond topography



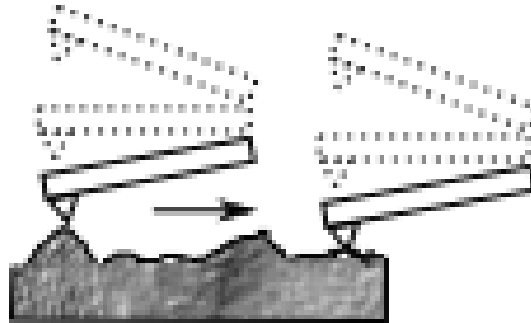
# Introduction

The interaction between the AFM probe tip and the surface may include additional electric, magnetic, indentation, adhesive, and capillary forces. Some of them are the basis for measuring modes that extend the applicability of atomic force microscopy. This presentation presents selected methods of AFM work divided by the way the measurement is performed.

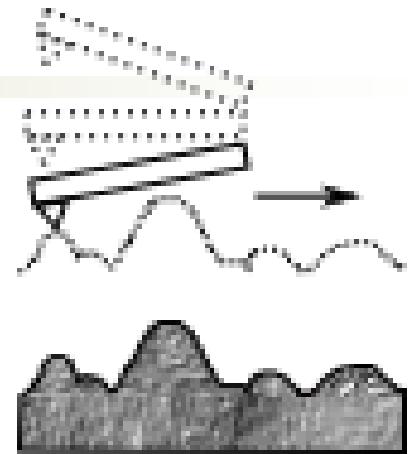
# Measurement modes



Contact



Vibrating mode



Many pass

■ **LFM**: lateral forces microscopy

■ **SSRM**: scanning spreading resistance microscopy

■ **SThM**: scanning thermal microscopy

■ **FMM**: force modulation microscopy

■ **AFAM**: atomic force acoustic microscopy

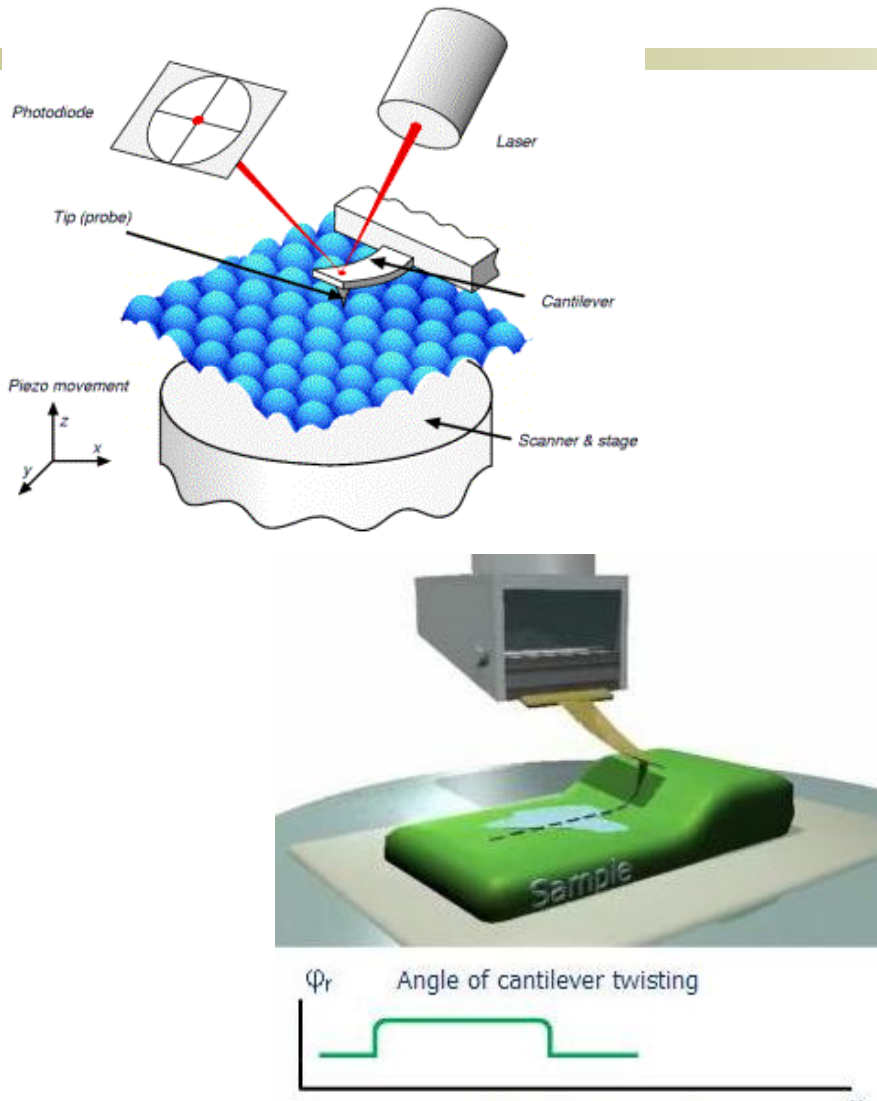
■ **MFM**: magnetic force microscopy

■ **EFM**: electric force microscopy

■ **SKM**: scanning Kelvin microscopy

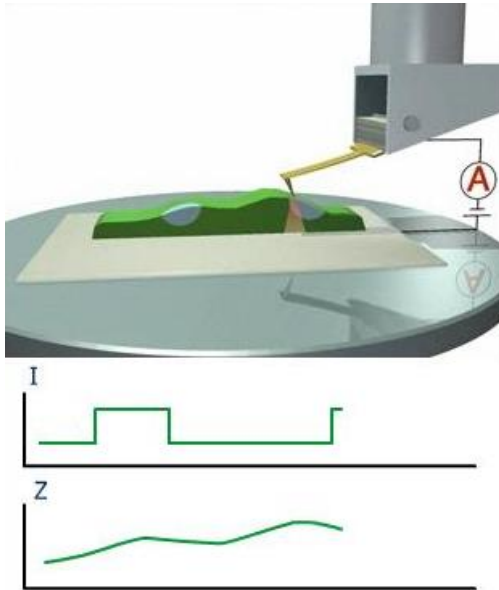
■ **SCM**: scanning capacitance microscopy

# Lateral forces imaging

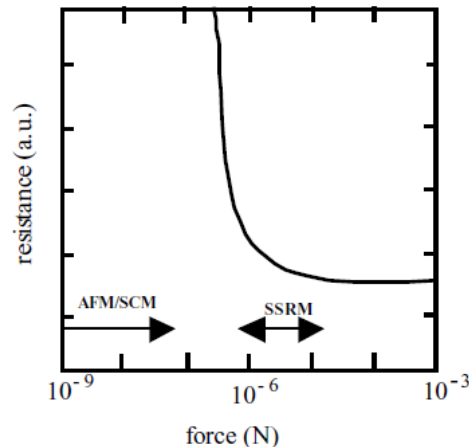
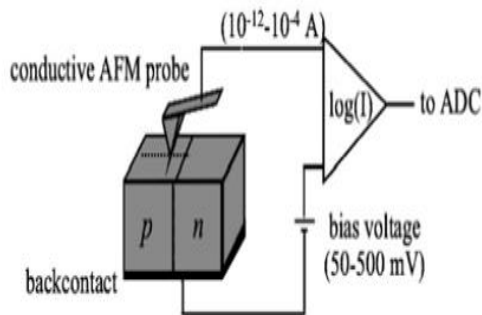


- The lateral force technique allows you to visualize the differences in friction force on the sample surface.
- During constant-force scanning, in addition to the bending force acting in the "z" direction, the friction forces in the "x" and "y" directions also affect the lever. The torsion angle of the lever is proportional to these forces. It is measured by the differential signal between the left and right quadrant photodiodes.

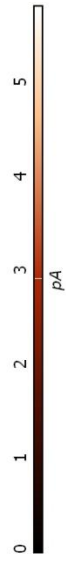
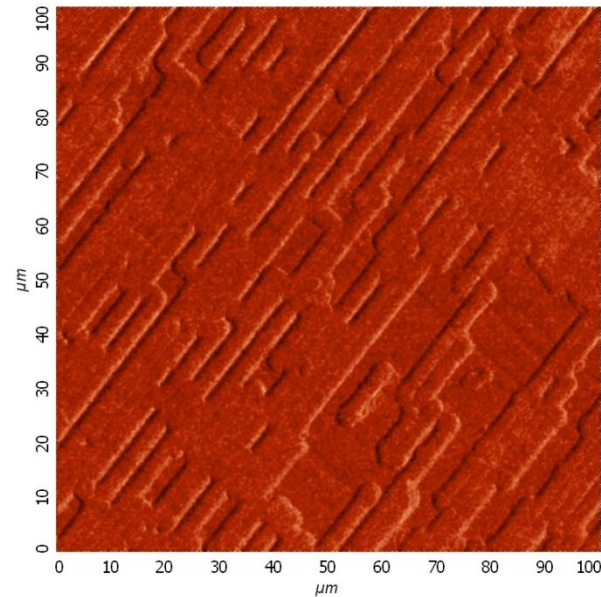
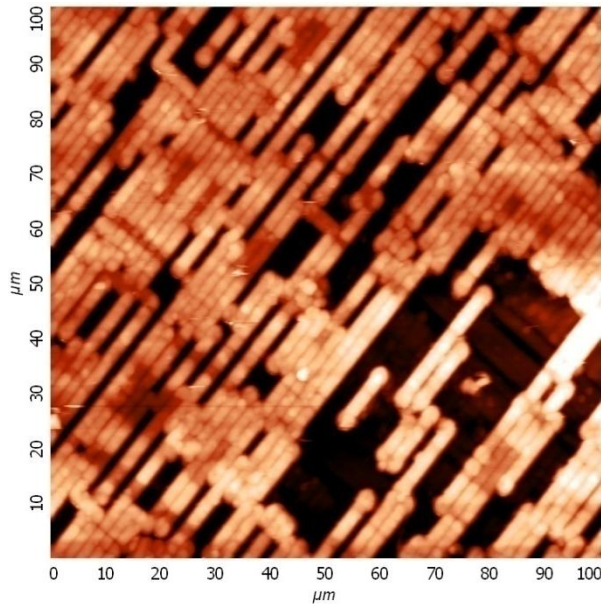
# Spreading resistance imaging



- Use of a conductive probe allows to measure the local electrical conductivity of a sample called "spreading resistance".
- When a constant voltage to the sample/tip junction is applied, assuming a constant contact force, the current flow determines local resistance of a small volume of material in the vicinity of the tip.



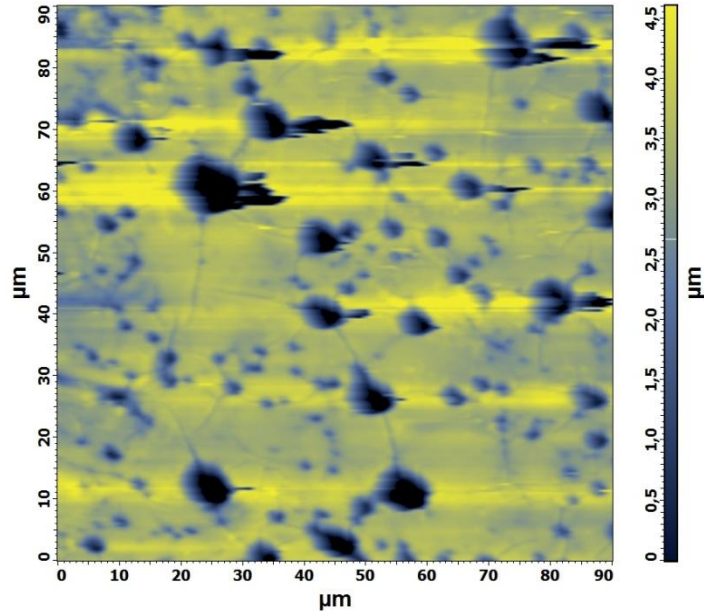
# Spreading resistance imaging



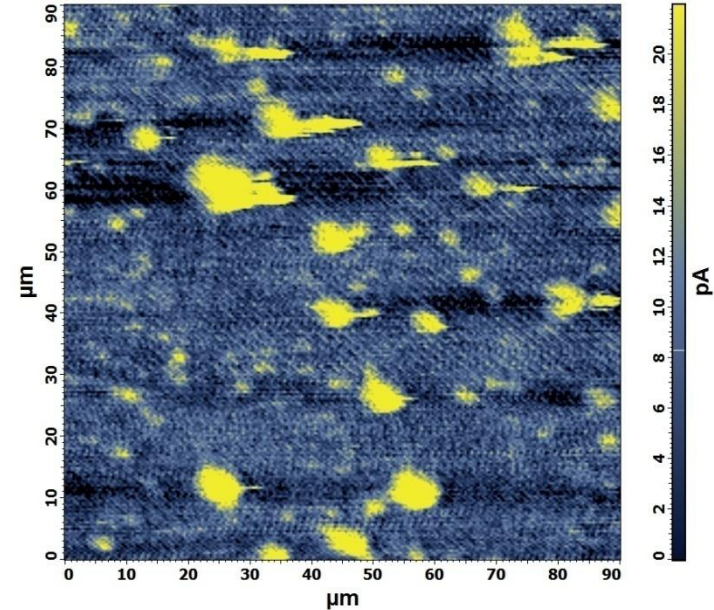
- Use of the spreading resistance measurement technique to study the conductivity distribution (right) on the surface of the integrated circuit (left).



# Alternating current imaging

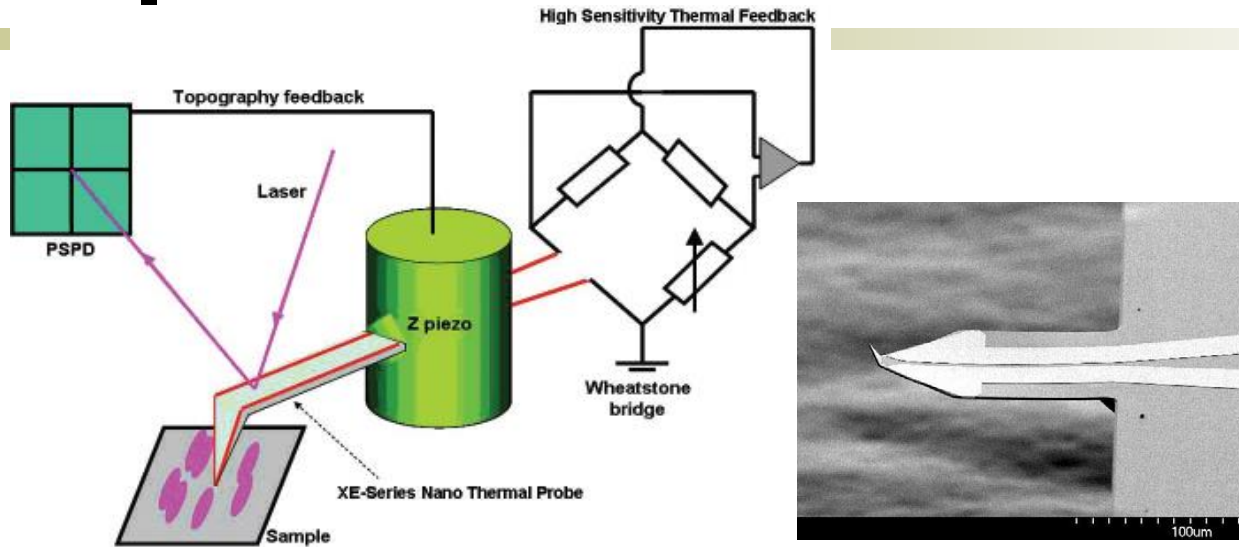


- Acrylic coating destroyed by exposure to 3% NaCl solution for 3 months.

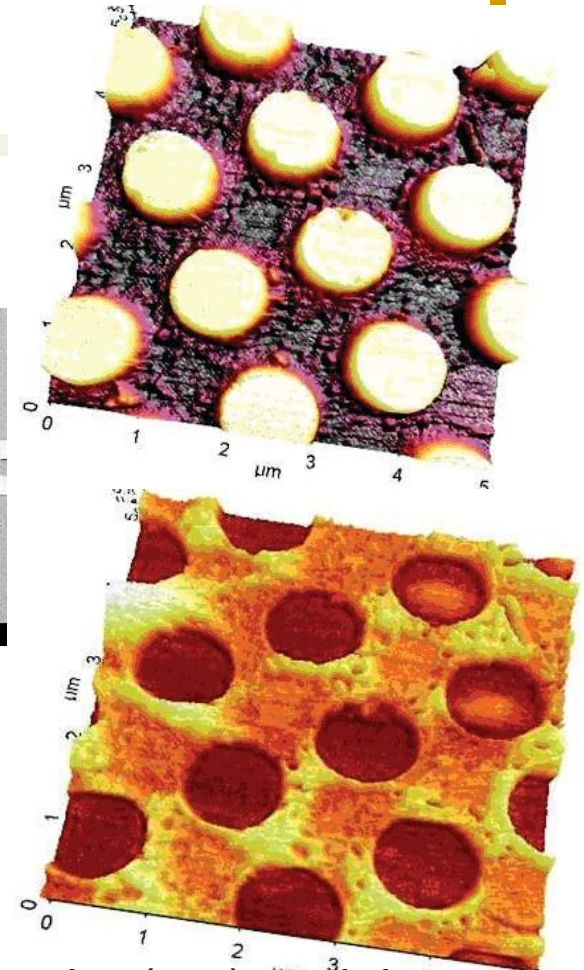
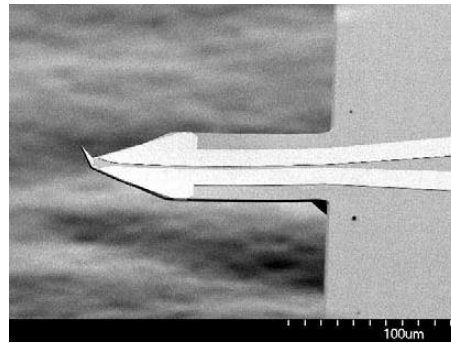


- Image of 3 kHz current magnitude for the same area.

# Scanning thermal microscopy



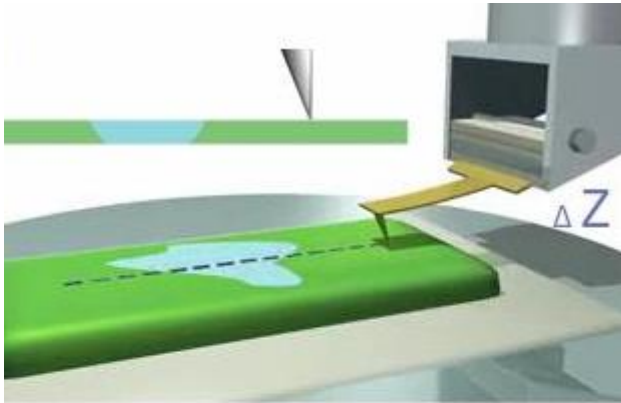
- Diagram of operation of the microscope in thermal measurement mode. The V-shaped probe contains a thermistor and is part of the Wheatstone bridge, allowing local measurement of the temperature.



- Image topography (top) and thermal conductivity (bottom) of sample in the form of polymer inclusions in silicone substrate



# Force modulation



Tip position



Cantilever deflection

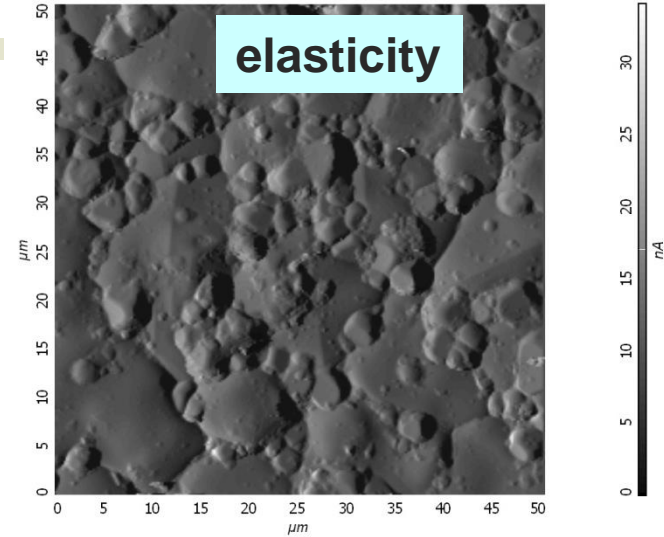
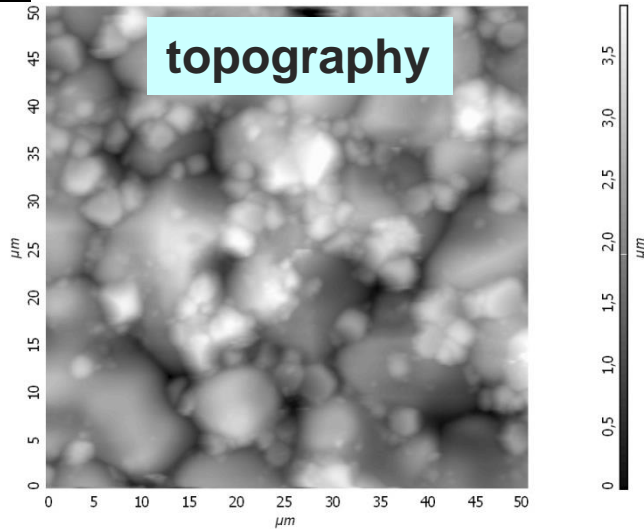


Stiffness

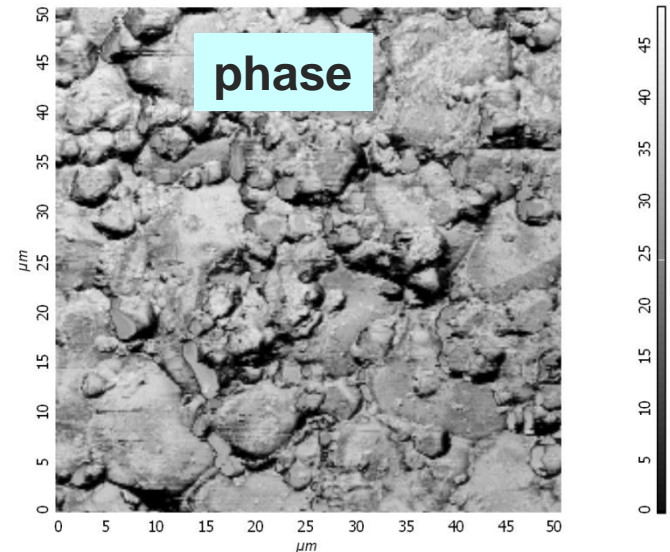


- In force modulation mode, the scanner performs periodic oscillations during constant-force scan. As a result, the free end of the lever makes an indentation of the surface of the sample. In areas with high hardness, the recess is negligible and the deflection of the levers is large. In regions with low hardness, the degree of indentation is higher.
- Modulation measurement allows to determine local changes in sample hardness.

# Force modulation

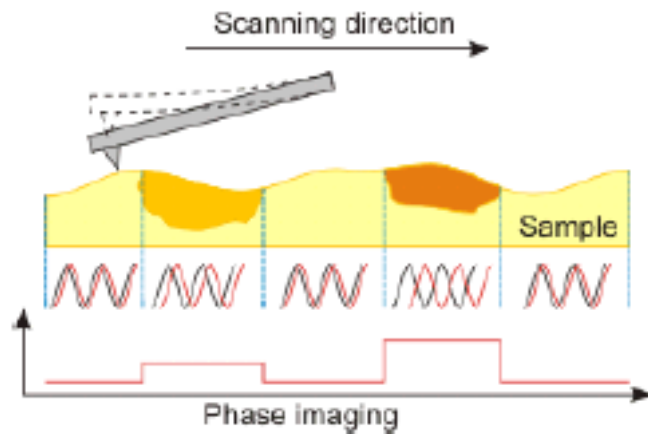


- Example of stiffness distribution of semiconductor material. The quality of the varistor produced from the presented plates is dependent on their granularity and hardness of the interstitial boundaries.

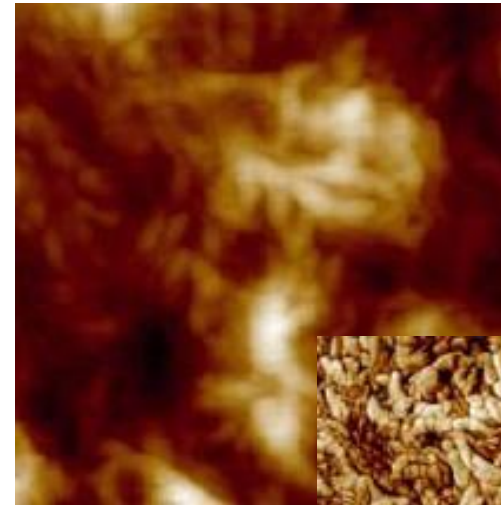


# Phase imaging

- This mode is usually performed concurrently with topographic imaging. It allows you to map surface properties such as friction, elasticity or adhesion.

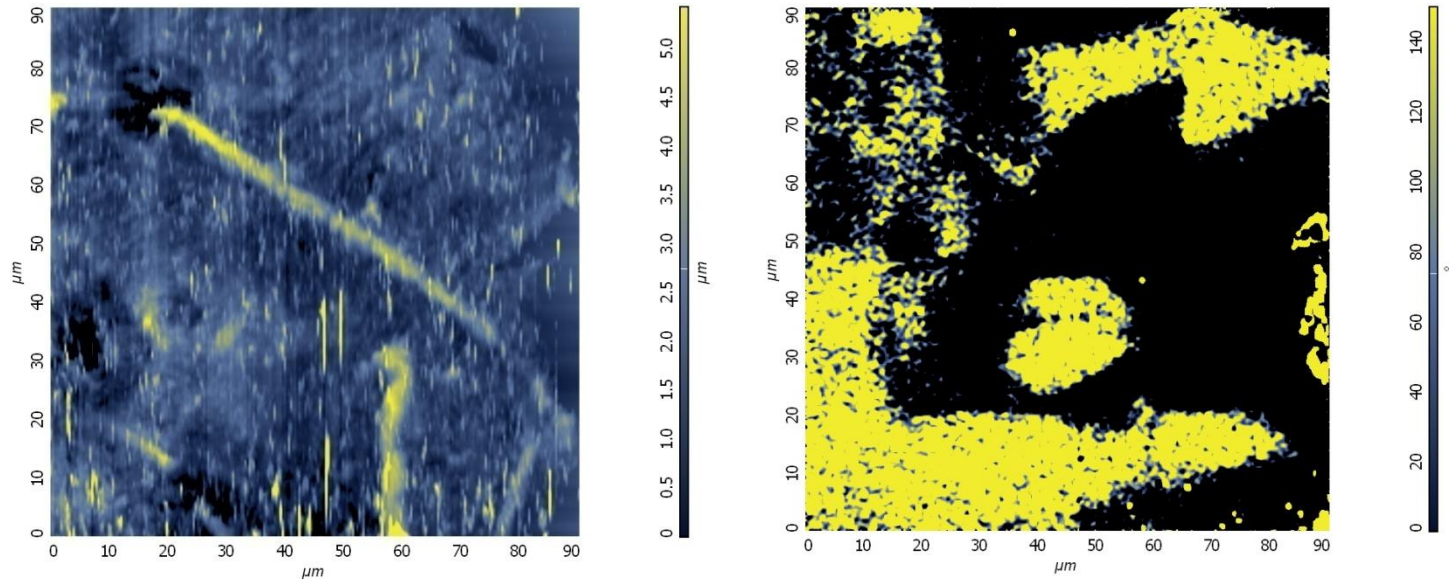


- Scheme of the measurement



- Topographic and phase image of polyethylene sample

# AFAM

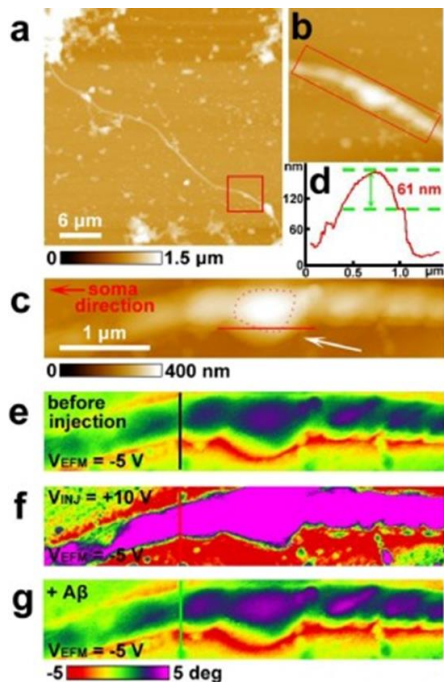


- The Atomic Force Acoustic Microscopy technique involves vibrating the sample under test. The vibrations are transferred to the tip and the cantilever in contact with the sample. Based on the vibration analysis, it is possible to differentiate areas with different mechanical properties as well as local hardness determination with submicron resolution.



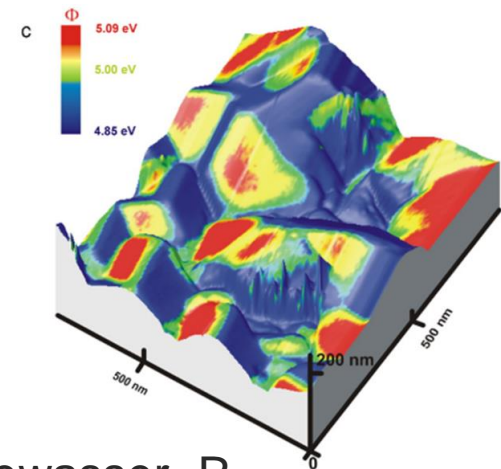
# Electrostatic force microscopy

- The EFM technique allows mapping of the spatial distribution of the electric field intensity vector. Between the conductive probe and the surface of the sample the voltage is applied producing the electric field.
- The measurement is performed in two passes. The topography is determined in the first one. The second scan is carried out along the route providing a constant distance between the sample and the probe. The distance in the second run must be sufficiently large to eliminate van der Waals short-range forces and leave only long distance electrical interference.



■ W. Zhao, W. Cui, S. Xu, Y. Wang, K. Zhang, D. Wang, L-Z. Cheong, F. Besenbacher, C. Shen, Ultramicroscopy, 196 (2019) 24.

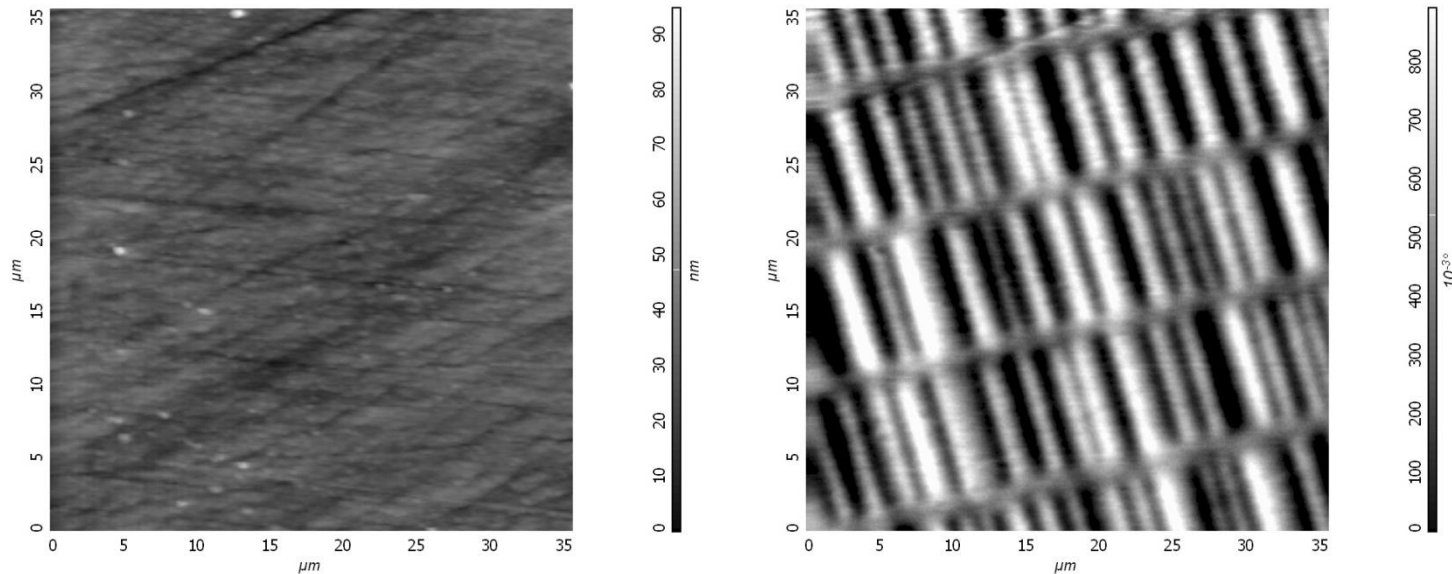
■ T. Glatzel, H. Steigert, S. Sadewasser, R. Klenk, M.C. Lux-Steiner, Thin Solid Films 480 (2005) 177.





# Magnetic force microscopy

- The MFM technique allows mapping of the spatial distribution of the magnetic field strength vector. The probe tip is covered with a layer of ferromagnetic material. Magnetic force imaging can be performed in both vibration and non-contact mode.



- Topographical and magnetic scan of hard disk surface

# Scanning Kelvin probe microscopy

1

- SKM is used to map the surface potential of sample  $\Phi(x)$ . It is based on the use of two passes. The first is the topographic one. During the second scan the potential is applied to the tip:

$$V_{tip} = V_{dc} + V_{ac} \sin(\omega t)$$

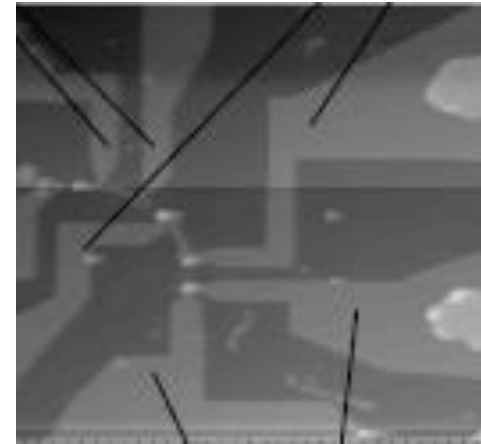
- The resultant force is:

$$F_{cap} = \frac{1}{2} (V_{tip} - \Phi(x))^2 \frac{dC}{dz}$$

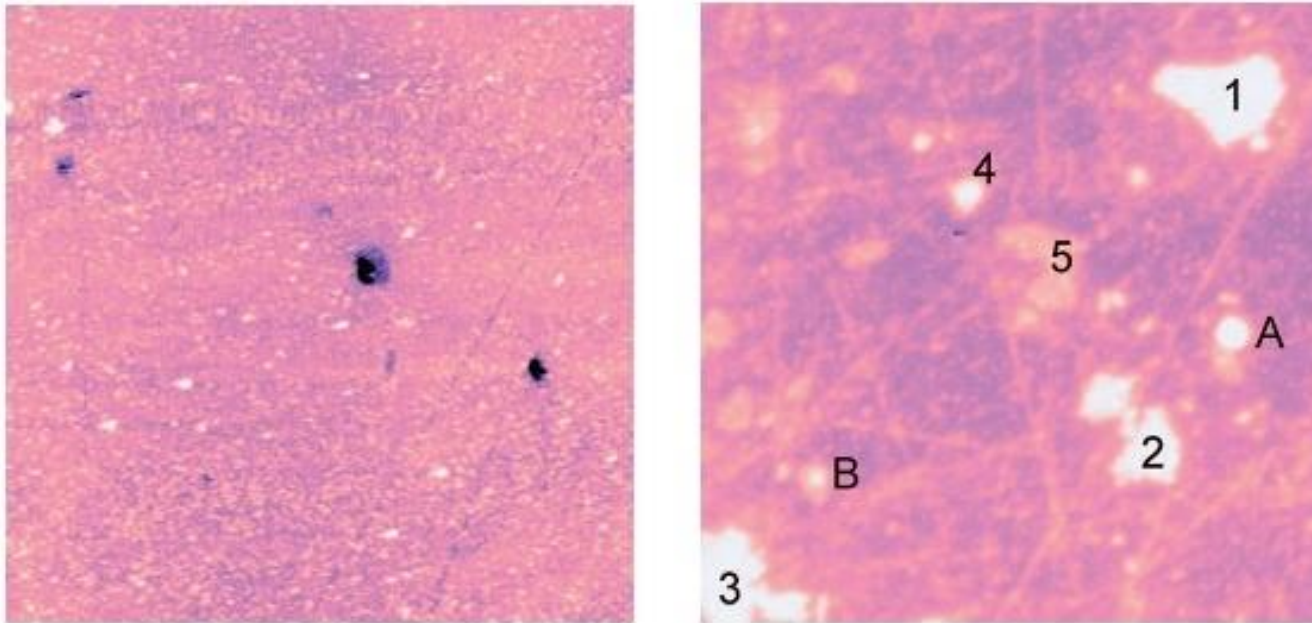
- The first harmonic force causes the lever oscillations:

$$F_{cap,1\omega} = \frac{dC}{dz} (V_{dc} - \Phi(x)) V_{ac} \sin(\omega t)$$

- Feedback feedback changes the  $V_{dc}$  value causing attenuation of oscillations. In such a situation  $V_{dc} = \Phi(x)$  so that the constant potential map reflects the distribution of surface potential.



# Metallographic investigations



- Image of the surface of the alloy sample AA2024-T3 (left) and distribution of surface potential (right image). The potential value of the Al-Cu-Mg intermetallic phase is unknown, although its presence is not detected in the topographic image.

# Scanning capacitance microscopy

- The technique is based on the use of two passes the same as in SKPM. Polarization of the the tip with the potential in the form:

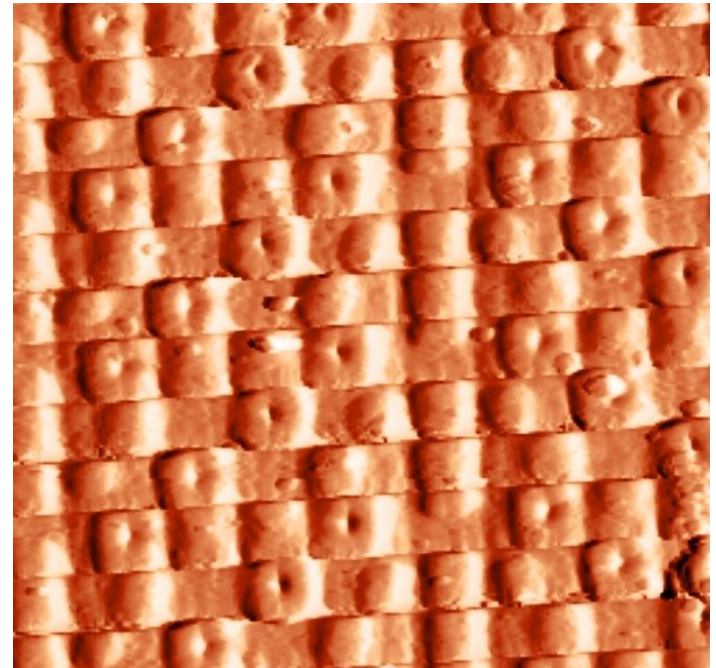
$$V_{tip} = V_{dc} + V_{ac} \sin(\omega t)$$

- Creates a capacitive force:

$$F_{cap} = \frac{1}{2} (V_{tip} - \Phi(x))^2 \frac{dC}{dz}$$

- The second harmonic of the force can be used to determine the capacitive contrast  $dC/dz$

$$F_{cap,2\omega} = \frac{1}{2} \frac{dC}{dz} V_{ac}^2 \sin(2\omega t)$$



# Further information

The screenshot shows the NT-MDT website page for 'Constant Force mode'. The page layout includes a top navigation bar with links like 'Products', 'Application areas', 'Learning center', 'Customer support', 'About company', 'News', and 'Contacts'. A sidebar on the left lists various SPM techniques, including 'AFM' and 'Contact techniques'. The main content area features a diagram of an AFM tip interacting with a sample, accompanied by text explaining the 'Constant Force mode' operation. The text describes how the cantilever deflection under scanning reflects repulsive force and how the DFL signal is used as a parameter for topography measurement. A sidebar on the left promotes a 'Special Offer Spring 2012' for 'AFM probes and gratings with every week!'. The page also includes a 'References' section with a citation by Magonov and Sergeev.

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AFM

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  - Constant Force mode
  - Contact Error mode
  - Lateral Force Imaging
  - Spraying Resistance Imaging
- ac Contact techniques
- Semiconduct techniques
- Non-Contact techniques
- Many-pass techniques

Spectroscopies

- SNOM
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- SPM Basics
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**NT-MDT**  
Special Offer  
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every week!

### Constant Force mode

In **Contact mode** of operation the cantilever deflection under scanning reflects repulsive force acting upon the tip.

Repulsion force  $F$  acting upon the tip is related to the cantilever deflection value  $x$  under Hooke's law:  $F = -kx$ , where  $k$  is cantilever spring constant. The spring constant value for different cantilevers usually vary from 0.01 to several N/m.

In our units the vertical cantilever deflection value is measured by means of the optical registration system and converted into electrical signal DFL. In contact mode the DFL signal is used as a parameter characterizing the interaction force between the tip and the surface. There is a linear relationship between the DFL value and the force. In Constant Force mode of operation the deflection of the cantilever is maintained by the feedback circuitry on the preset value. So vertical displacement of the scanner under scanning reflects topography of sample under investigation.

Constant Force mode has some advantages and disadvantages.

Main advantage of Constant Force mode is possibility to measure with high resolution simultaneously with topography some other characteristics - **Friction Forces**, **Spraying Resistance** etc.

Constant Force mode has also some disadvantages. Speed of scanning is restricted by the response time of feedback system. When exploring soft samples (like polymers, biological samples, Langmuir-Blodgett films etc.) they can be destroyed by the scratching because the probe scanning tip is in direct contact with the surface. Thereunto under scanning soft unhomogeneous samples the local flexure of sample surface varies. As a result acquired topography of the sample can prove distorted. Possible existence of substantial capillary forces imposed by a liquid adsorption layer can decrease the resolution.

#### References

1. Magonov, Sergei N. Surface Analysis with STM and AFM. Experimental and Theoretical Aspects of Image Analysis. VCH 1996.

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